

| Form PTO-1449 | | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | | ATTY. DOCKET NO. M72-1748 | SERIAL NO. 09/879,231 | | |
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| LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) | | | | | APPLICANT Caro J. Denderian | | | |
| | | | | | PRIORITY FILING DATE June 11, 2001 | GROUP 2815 | | |
| U.S. PATENT DOCUMENTS | | | | | | | | |
| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate | |
| TL | AA | 2002/0064915A1 | 05/2002 | Kiumura | | | | |
| TL | AB | 2001/0023110A1 | 09/2001 | Fukuzumi et al | | | | |
| | AC | | | | | | | |
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| FOREIGN PATENT DOCUMENTS | | | | | | | | |
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| | AO | | | | | | | |
| OTHER REFERENCES (Including Author, Title, Date, Patent Pages, Etc.) | | | | | | | | |
| TL | AP | | A.W. Ott, et al. "Atomic layer controlled deposition of Al ₂ O ₃ films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pp. 128-136. | | | | | |
| | AQ | | | | | | | |
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| EXAMINER <u>TL</u> | | | | DATE CONSIDERED <u>2/04/03</u> | | | | |
| <small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small> | | | | | | | | |